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l10 and l1 and l2 and l3 and l7

2

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l10 and l1 and l2 and l3 and l7

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| USPT           | l10 and l1 and l2 and l3 and l7           | 2                | <u>L12</u>      |
| USPT           | l9 and l10                                | 0                | <u>L11</u>      |
| USPT           | revers\$3 with (temperature adj gradient) | 190              | <u>L10</u>      |
| USPT           | l1 and l2 and l3 and l4 and l7            | 434              | <u>L9</u>       |
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| USPT           | l1 and l2 and l3 and l4 and l5            | 22               | <u>L6</u>       |
| USPT           | (duct or tube) with refractory            | 4184             | <u>L5</u>       |
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| USPT           | heaters or heating near2 means            | 116403           | <u>L3</u>       |
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| USPT           | vapor adj deposition or cvd               | 66034            | <u>L1</u>       |

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|---|------|-----|--------|-------------------------------------|-------|---------------------|
| 1 | IS&R | L1  | 0      | ("vapor adj deposition or cvd").PN. | USPAT | 2001/06/21<br>11:24 |
| 2 | BRS  | L2  | 64371  | vapor adj deposition or cvd         | USPAT | 2001/06/21<br>11:29 |
| 3 | BRS  | L3  | 346077 | substrate                           | USPAT | 2001/06/21<br>11:30 |
| 4 | BRS  | L4  | 36505  | heaters or heating near2 means      | USPAT | 2001/06/21<br>11:38 |
| 5 | BRS  | L5  | 210268 | radiation                           | USPAT | 2001/06/21<br>11:39 |
| 6 | BRS  | L6  | 3309   | (duct or tube) with refractory      | USPAT | 2001/06/21<br>11:39 |
| 7 | BRS  | L7  | 5      | 2 and 3 and 4 and 5 and 6           | USPAT | 2001/06/21<br>11:45 |
| 8 | BRS  | L8  | 0      | leycuras adj andre.in.              | USPAT | 2001/06/21<br>11:45 |
| 9 | BRS  | L9  | 0      | leycuras.in.                        | USPAT | 2001/06/21<br>11:46 |